Inventor:

Gurtej S. Sandhu et al.

Title:

Methods of Forming Capacitor Constructions

Assignee:

Micron Technology, Inc.

Attorney Docket No. MI22-2521

INFORMATION DISCLOSURE STATEMENT

PURSUANT TO 37 C.F.R. §§ 1.56, 1.97 AND 1.98

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is

directed to the United States patents and other references listed on the attached

Form PTO-1449. No admission is made regarding whether all the submitted

references are prior art.

The listed references were cited by, or submitted to, the Office in the

parent, co-pending application of the above-identified application. The above-

identified application is a continuation application of co-pending application Serial

No. 10/222,330, filed August 15, 2002. Such prior disclosure is sufficient for

the above-identified application as far as copies of the references are concerned.

37 C.F.R. § 1.98(d) and MPEP § 609(2).

Citation of these references is respectfully requested.

Respectfully submitted,

Dated: Mouch 8, 2004

Jennifer /J. Ta

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Form PTO-144	19			ATTY. DOCKET N MI22-2521		SERIAL NO. (PRIORITY) 10/222.330						
LIST OF ART CITED (Use several sheets						APPLICANT Gurtej S. Sandhu et						
					FILING DATE (PR August 15, 2002		IORITY)	GROU 2813		JP (PRIORITY)		
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·	AR	Cranciun et al., "Low Temperature Growth of Barium Strontium Titanate Films by Ultraviolet-Assisted Pulsed Laser Deposition", Mat. Res. Symp. Vol. 617, pgs. J3.21.1-J3.21.6, 2000. Year is sufficiently early such that the month is not an issue.										
	AS	AS										
EXAMINER	DATE CONSIDERED											
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.												